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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Joseph Young J. PAIK

Serial No. 10/665,165

Filed: September 18, 2003



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: Group Art Unit:  
:  
: Examiner:

For: FEEDBACK CONTROL OF A CHEMICAL MECHANICAL POLISHING PROCESS  
FOR MULTI-LAYERED FILMS

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Honorable Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom. Copies of any cited U.S. Patents and U.S. Patent Publications are not being submitted in accordance with 37 CFR 1.98(a)(2)(i).

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

In accordance with 37 C.F.R. § 1.97(g) and (h), the filing of this IDS should not be construed as a representation that a search had been made or that information cited is, or is considered to be, material to patentability as defined in 37 C.F.R. § 1.56 (b), or that any cited document listed or attached is (or constitutes) prior art. Unless otherwise indicated, the date of

publication indicated for an item is taken from the face of the item, and Applicant reserves the right to prove that the date of publication is in fact different.

No fee is believed to be required; however, the Commissioner is authorized to charge any deficiency in any fees pursuant to 37 CFR § 1.17 associated with this communication and to credit any excess payment to Deposit Account No. 08-0219.

Respectfully submitted,

WILMER CUTLER PICKERING HALE AND DORR LLP

A handwritten signature in black ink, appearing to read "Scott M. Alter".

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<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  (PTO-1449)				ATTY. DOCKET NO. 007734 USA/ FPS/MMCS/APC		SERIAL NO. 10/665,165	
				APPLICANT Joseph Young J. PAIK			
				FILING DATE September 18, 2003		GROUP	
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	5,975,994	11/02/99	Sandhu et al.			06/11/97	
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	6,230,069 B1	05/08/01	Campbell et al.			06/26/98	
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	6,725,402 B1	04/20/04	Coss, Jr. et al.			07/31/00	
EXAMINER				DATE CONSIDERED			

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

<p align="center"><b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b></p> <p align="center">(PTO-1449)</p> 		ATTY. DOCKET NO. 007734 USA/ FPS/MMCS/APC	SERIAL NO. 10/665,165
		APPLICANT Joseph Young J. PAIK	
		FILING DATE September 18, 2003	GROUP
<b>OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>			
	IslamRaja, M. M., C. Chang, J. P. McVittie, M. A. Cappelli, and K. C. Saraswat. May/June 1993. "Two Precursor Model for Low-Pressure Chemical Vapor Deposition of Silicon Dioxide from Tetraethylorthosilicate." <i>J. Vac. Sci. Technol. B</i> , Vol. 11, No. 3, pp. 720-726.		
	Kim, Eui Jung and William N. Gill. July 1994. "Analytical Model for Chemical Vapor Deposition of SiO <sub>2</sub> Films Using Tetraethoxysilane and Ozone" (Abstract). <i>Journal of Crystal Growth</i> , Vol. 140, Issues 3-4, pp. 315-326.		
	Guo, R.S, A. Chen, C.L. Tseng, I.K. Fong, A. Yang, C.L. Lee, C.H. Wu, S. Lin, S.J. Huang, Y.C. Lee, S.G. Chang, and M.Y. Lee. June 16-17, 1998. "A Real-Time Equipment Monitoring and Fault Detection System." <i>Semiconductor Manufacturing Technology Workshop</i> , pp. 111-121.		
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	July 15, 2004. Office Action for U.S. Serial No. 10/172,977, filed June 18, 2002.		
	August 2, 2004. Office Action for U.S. Serial No. 10/174,377, filed June 18, 2002.		
	August 9, 2004. Written Opinion for PCT Serial No. PCT/US02/19063.		
	August 18, 2004. International Preliminary Examination Report for PCT Serial No. PCT/US02/19116.		
	August 24, 2004. Office Action for U.S. Serial No. 10/135,405, filed May 1, 2002.		
	August 25, 2004. Office Action for U.S. Serial No. 09/998,384, filed November 30, 2001.		
	September 9, 2004. Written Opinion for PCT Serial No. PCT/US02/21942.		
	September 16, 2004. International Preliminary Examination Report for PCT Serial No. PCT/US02/24859.		
EXAMINER		DATE CONSIDERED	

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